



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the Application of: **Koji NOZAKI et al.**

Group Art Unit: **1752**

Application Number: **10/623,679**

Examiner: **Amanda C. Walke**

Filed: **July 22, 2003**

Confirmation Number: **5083**

For: **RESIST PATTERN THICKENING MATERIAL, RESIST PATTERN  
AND PROCESS FOR FORMING THE SAME, AND  
SEMICONDUCTOR DEVICE AND PROCESS FOR  
MANUFACTURING THE SAME**

Attorney Docket Number: **030891**

Customer Number: **38834**

**SUBMISSION UNDER 37 C.F.R. §1.114**

Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

November 13, 2006

Sir:

This Submission is being filed concurrently with a Request for Continued Examination pursuant to 37 C.F.R. §1.114.

**Amendments to the Claims** begin on page 2 of this paper.

**Remarks** begin on page 11 of this paper.

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